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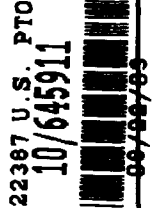
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3. Nature of conveyance:

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4. Application number(s) or patent number(s):

If this is being filed together with a new application, the execution date of the application is:

June 9, 17, 20,
 23, 2003

A. Patent Application Number(s):

10/645911

B. Patent Number(s):

Additional numbers attached? NO

5. Name and address of party to whom correspondence concerning document should be mailed:

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6. Total number of applications/patents involved: 1

7. Total fee (37 C.F.R. § 3.41):

\$40.00

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8. Deposit account number:

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AUG 22 2003

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PATENT

REEL: 014424 FRAME: 0822

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hisatsugu KURITA et al.
Title: SILICON WAFER CLEANING METHOD
Appl. No.: Unassigned
Filing Date: AUG 22 2003
Examiner: Unassigned
Art Unit: Unassigned

CLAIM FOR CONVENTION PRIORITY

Commissioner for Patents
PO Box 1450
Alexandria, Virginia 22313-1450

Sir:

The benefit of the filing dates of the following prior foreign applications filed in the following foreign country is hereby requested, and the right of priority provided in 35 U.S.C. § 119 is hereby claimed.

In support of this claim, filed herewith are certified copies of said original foreign applications:

- Japanese Patent Application No. 2002-259579 filed 09/05/2002.
- Japanese Patent Application No. 2002-299769 filed 10/15/2002.
- Japanese Patent Application No. 2003-005323 filed 01/14/2003.

Respectfully submitted,

Date AUG 22 2003

By Richard L. Schwaab

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